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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 1632**  
Norio KIMURA et al. : Docket No. 2001-0660A  
Serial No. 09/864,208 : Group Art Unit 1763  
Filed May 25, 2001 : Examiner Sylvia MacArthur

SUBSTRATE POLISHING APPARATUS  
AND SUBSTRATE POLISHING METHOD

**ELECTION OF INVENTION**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action of January 8, 2004, applicants in the above-referenced application hereby elect the invention Group II corresponding to claims 16-37.

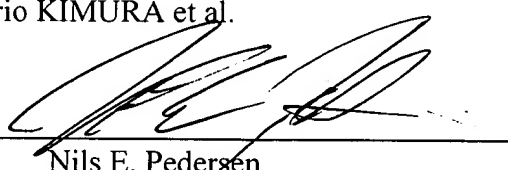
An early and favorable action on their merits is requested.

Respectfully submitted,

Norio KIMURA et al.

THE COMMISSIONER IS AUTHORIZED  
TO CHARGE ANY DEFICIENCY IN THE  
FEES FOR THIS PAPER TO DEPOSIT  
ACCOUNT NO. 23-0975

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